

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Jack Y. Jau et al.

Application No.:

Filed:

For: METHOD AND APPARATUS FOR
SCANNING SEMICONDUCTOR
WAFERS USING A SCANNING
ELECTRON MICROSCOPE

Customer No.: 20350

Confirmation No.:

Examiner: James P. Hughes

Technology Center/Art Unit: 2881

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the above-referenced application, please enter the following amendments and remarks:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.